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<b>INFORMATION DISCLOSURE STATEMENT</b>				<b>APPLICANT(S): Card et al.</b>					
				<b>SERIAL NO.: 10/656,607</b>					
				<b>FILING DATE: 9/5/03 GROUP: Not yet assigned</b>					
<b>U.S. PATENT DOCUMENTS</b>									
EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE		
QJB	A1	5,467,883	11/21/95	Frye et al.	216	60	11/27/93		
QJB	A2	5,559,690	9/24/96	Keeler et al.	364	164	9/16/94		
QJB	A3	5,654,903	8/5/97	Reitman et al.	364	551.01	11/7/95		
QJB	A4	5,740,033	4/14/98	Wassick et al.	364	149	10/13/92		
QJB	A5	6,268,226	7/31/01	Angell et al.	438	16	6/30/99		
<b>FOREIGN PATENT DOCUMENTS</b>									
EXAM. INIT.		DOCUMENT NUMBER	DATE	COUNTRY CODE	CLASS	SUB CLASS	FILING DATE	ABSTRACT ONLY	ENGLISH LANG (Y/N)
QJB	B1	WO 01/57605	8/9/01	WO	G05B	13/04	1/11/01	N	Y
QJB	B2	DE196 37 917 A1	3/19/98	DE	G05B	13/04	9/17/96	Y	
<b>OTHER ART, JOURNAL ARTICLES, ETC.</b>									
EXAM. INIT.	<b>OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication)</b>								
QJB	C1	Card et al., "Dynamic Neural Control for Plasma Etch Process," <u>IEEE Transactions on Neural Networks</u> , (1997).							
QJB	C2	Card et al., "Impacts of Maintenance Input on the Prediction Accuracy of an APC Controller," Presentation at AEC/APC Symposium XIV (September 9-11, 2002).							
QJB	C3	Card et al., "Advanced Analysis of Dynamic Neural Control Advisories for Process Optimization and Parts Maintenance," Presentation at AEC/APC Symposium XIV (September 9-11, 2002).							
QJB	C4	Dillon et al., "Guest Editorial Everyday Applications of Neural Networks," <u>IEEE Transactions on Neural Networks</u> , 8:4 (July 1997).							
QJB	C5	Hatzipantelis et al., "Comparing Hidden Markov Models with Artificial Neural Network Architectures for Condition Monitoring Applications," <u>Artificial Neural Networks</u> , 26-28, Conference Publication No. 409 (June 1995).							



CJB	C6	Kim et al., "Intelligent Control of Via Formation by Photosensitive BCB for MCM-L/D Applications," <u>IEEE Transactions on Semiconductor Manufacturing</u> , 12:503 (1999).
CJB	C7	Konstantopoulos et al., "Controllers with Diagnostic Capabilities. A Neural Network Implementation. Journal of Intelligent and Robotic Systems," Department of Electrical Engineering, University of Notre Dame, IN 12: 197-228 (1995).
CJB	C8	Moyne, "AEC/APC Vision: A Research and Suppliers' Point of View," 3 <sup>rd</sup> Annual European AEC/APC Conference Proceedings (2002).
CJB	C9	Rietman et al., "A Study on $\mathcal{R}^m \rightarrow \mathcal{R}^1$ Maps: Application to a 0.16- $\mu$ m Via Etch Process Endpoint," <u>IEEE</u> (2000).
CJB	C10	Rietman et al., "A System Model for Feedback Control and Analysis of Yield: A Multistep Process Model of Effective Gate Length, Poly Line Width, and IV Parameters", <u>IEEE</u> (2001).
CJB	C11	Rietman, "Neural Networks in Plasma Processing," <u>Journal of Vacuum Science and Technology: Part B, IEEE Transactions on Semiconductor Manufacturing</u> , 14:1 (2001).
CJB	C12	Smyth et. al., "Hidden Markov Models and Neural Networks for Fault detection in Dynamic Systems," California Institute of Technology (1993).
CJB	C13	Zhang et al, "Control of Spatial Uniformity in Microelectronics Manufacturing: An Integrated Approach," Proceedings of AEC/APC (2000).
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	DATE CONSIDERED	20 May 2005